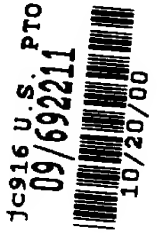


#5418-01

- 1 -

Docket: 0819-442

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re New Patent Application of)
Akihiko ISHIBASHI et al.)
Japanese Priority Application No. 11-299640) Attn: Applications
Japanese Priority Date: October 21, 1999) Branch
For: METHOD OF FABRICATING)
NITRIDE SEMICONDUCTOR)
DEVICE) Date: October 20, 2000

INFORMATION DISCLOSURE STATEMENT

Honorable Assistant Commissioner for Patents
Washington, D.C. 20231

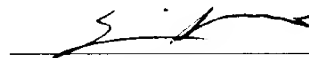
Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application.

Copies of the references are submitted herewith in accordance with 37

C.F.R. 1.98(a).

Respectfully submitted,



Eric J. Robinson
Registration No. 38,285

NIXON PEABODY LLP
8180 Greensboro Drive, Suite 800
McLean, Virginia 22102
(703) 790-9110